

US007495199B2

# (12) United States Patent

#### Jankowiak

### (10) Patent No.: US 7

## US 7,495,199 B2

### (45) **Date of Patent:**

Feb. 24, 2009

#### (54) MEMS RADIOMETER

(75) Inventor: Patrick Jankowiak, Dallas, TX (US)

(73) Assignee: STMicroelectronics, Inc., Carrollton,

TX (US)

(\*) Notice: Subject to any disclaimer, the term of this

patent is extended or adjusted under 35

U.S.C. 154(b) by 315 days.

(21) Appl. No.: 11/351,935

(22) Filed: Feb. 10, 2006

#### (65) Prior Publication Data

US 2007/0187603 A1 Aug. 16, 2007

(51) Int. Cl. G01J 1/00 (2006.01) G01J 1/04 (2006.01)

(52) **U.S. Cl.** ...... **250/200**; 356/216; 356/213;

250/336.1

#### (56) References Cited

#### U.S. PATENT DOCUMENTS

| 3,819,419 | A *          | 6/1974  | Loose 136/213             |
|-----------|--------------|---------|---------------------------|
| 5,719,324 | $\mathbf{A}$ | 2/1998  | Thundat et al.            |
| 5,977,544 | A *          | 11/1999 | Datskos et al 250/338.1   |
| 6,118,124 | A            | 9/2000  | Thundat et al.            |
| 6,312,959 | B1           | 11/2001 | Datskos                   |
| 6,444,972 | B1 *         | 9/2002  | Datskos et al 250/216     |
| 6,457,360 | B1           | 10/2002 | Daraktchiev et al.        |
| 6,636,676 | В1           | 10/2003 | Renn                      |
| 6,851,297 | B2           | 2/2005  | Cunningham et al.         |
| 6,872,947 | В1           | 3/2005  | Greywall                  |
| 6,954,579 | B2           | 10/2005 | Hsu                       |
| 7,154,077 | B2 *         | 12/2006 | Miklatzky et al 250/214 C |
| 7,324,323 | B2 *         | 1/2008  | Aksyuk et al 361/287      |
|           |              |         |                           |

#### FOREIGN PATENT DOCUMENTS

WO WO 97/26556 7/1997

#### OTHER PUBLICATIONS

Datskos, et al., "Photoinduced and thermal stress in silicon microcantilevers," Applied Physics Letters, AIP, American Institute of Physics, Melville, NY, US, vol. 73, No. 16, Oct. 19, 1998, pp. 2319-2321.

Sulfridge, et al., "Optical Actuation of a Bistable MEMS," Journal of Microelectromechanical Systems, IEEE Service Center, Piscataway, NJ, US, vol. 11, No. 5, Oct. 2002; XP011064800; ISSN: 1057-7157. European Search Report and Written Opinion, EP 07 25 0536, dated Oct. 8, 2007.

#### \* cited by examiner

Primary Examiner—David P Porta Assistant Examiner—Yara N Green (74) Attorney, Agent, or Firm—Lisa K. Jorgenson; Andre M. Szuwalski

#### (57) ABSTRACT

A radiometer sensor includes a target plate and a micromechanical spring which supports the target plate above a base support. This construction allows for displacement of the target plate in a direction perpendicular to the base support in response to radiation which is received by a top surface of the target plate. The sensor is enclosed within a housing that defines a sealed interior chamber within which a vacuum has been drawn. The target plate preferably is non-deformable in response to received radiation. Capacitive or piezoelectric sensors are provided to detect the displacement of the target plate, and the measured displacement is correlated to determine a received radiation level. Radiometer sensor output signals are quantized and signal processed so as to make a radiation level determination.

#### 33 Claims, 3 Drawing Sheets

